



Docket No. 0160-0193-0 PCT

#7/US
10/3/01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Hiroshi IKEDA, ET AL.

GAU: 1754

SERIAL NO: 09/463,961

EXAMINER: VANNOY, T.

FILED: MAY 25, 2000

FOR: METHOD AND APPARATUS FOR PROCESSING EXHAUST GAS OF SEMICONDUCTOR FABRICATION

**REQUEST FOR EXTENSION OF TIME
UNDER 37 C.F.R. 1.136**

ASSISTANT COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231

SIR:

RECEIVED

It is hereby requested that a one month extension of time be granted to **OCTOBER 19, 2001** for **OCT 0 3 2001**

☒ filing a response to the Official Action dated: JUNE 19, 2001

☐ responding to the requirements in the Notice of Allowability dated:

☐ filing the Formal Drawings. The Issue Fee due

has been timely filed.

☐ responding to the Notice to File Missing Parts of Application dated:

☐ filing a Notice of Appeal. A timely response to the final rejection, due

has been filed.

☐ filing an Appeal Brief. A Notice of Appeal was filed on:

☐ Applicant claims small entity status. See 37 CFR 1.27. Therefore, the fee amount shown below is reduced by one-half.

The required fee of **\$110.00** is enclosed herewith by check and any further charges may be made against the Attorney of Record's Deposit Account No. **15-0030**. A duplicate copy of this sheet is enclosed.

Respectfully Submitted,

OBLON, SPIVAK, McCLELLAND,
MAIER & NEUSTADT, P.C.

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